

## Electronic Supplementary Information (ESI)

### **Ambient Stable Solution-Processed Organic Field Effect Transistors from Electron Deficient Planar Aromatics: Effect of End-groups on Ambient Stability**

Indrajit Giri,<sup>a</sup> Sagar Biswas,<sup>a</sup> Shant Chhetri,<sup>a</sup> Anwasha Choudhuri,<sup>b</sup> Indrajit Mondal,<sup>c</sup> Satyaprasad P. Senanayak,<sup>c</sup> Parameswar Krishnan Iyer,<sup>b\*</sup> Debangshu Chaudhuri,<sup>a</sup> Ratheesh K. Vijayaraghavan<sup>a\*</sup>

<sup>a</sup> *Department of Chemical Sciences, Indian Institute of Science Education and Research Kolkata, Mohanpur, Nadia, West Bengal, India-741246.*

<sup>b</sup> *Centre for Nanotechnology, Indian Institute of Technology Guwahati, Assam, India-781039.*

<sup>c</sup> *Nanoelectronics and Device Physics Lab, School of Physical Sciences, National Institute of Science Education and Research, OCC of HBNI, Odisha, India-752050.*

Email: [pki@iitg.ac.in](mailto:pki@iitg.ac.in), [ratheesh@iiserkol.ac.in](mailto:ratheesh@iiserkol.ac.in)

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# 1. Characterization data:

## NMR data:

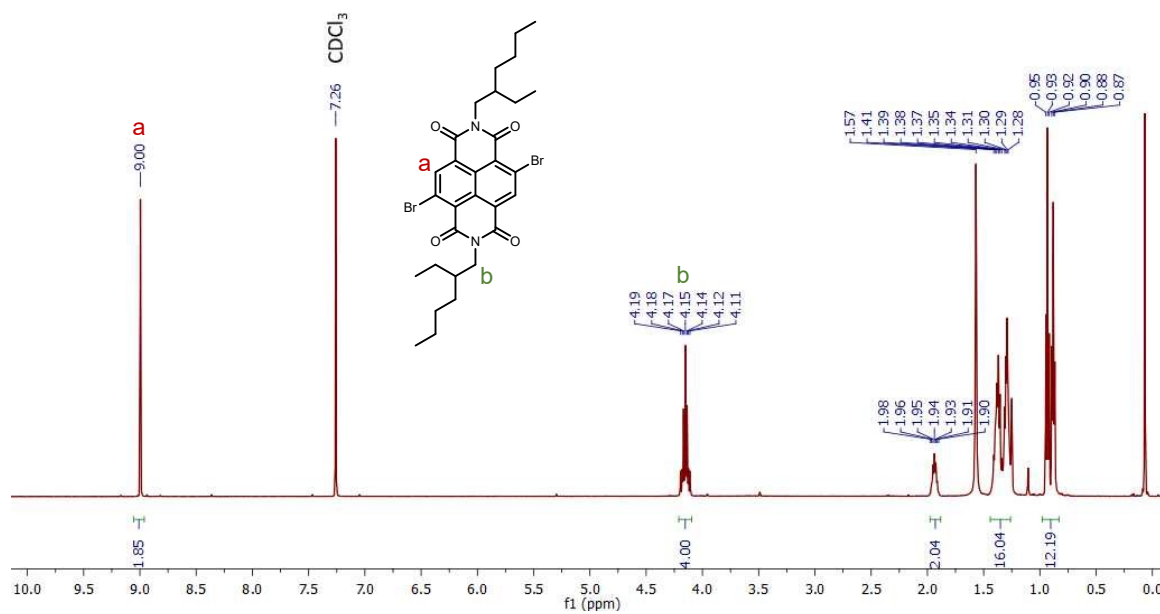


Figure S1. <sup>1</sup>H NMR spectrum of EHNDIBr<sub>2</sub> in CDCl<sub>3</sub>.

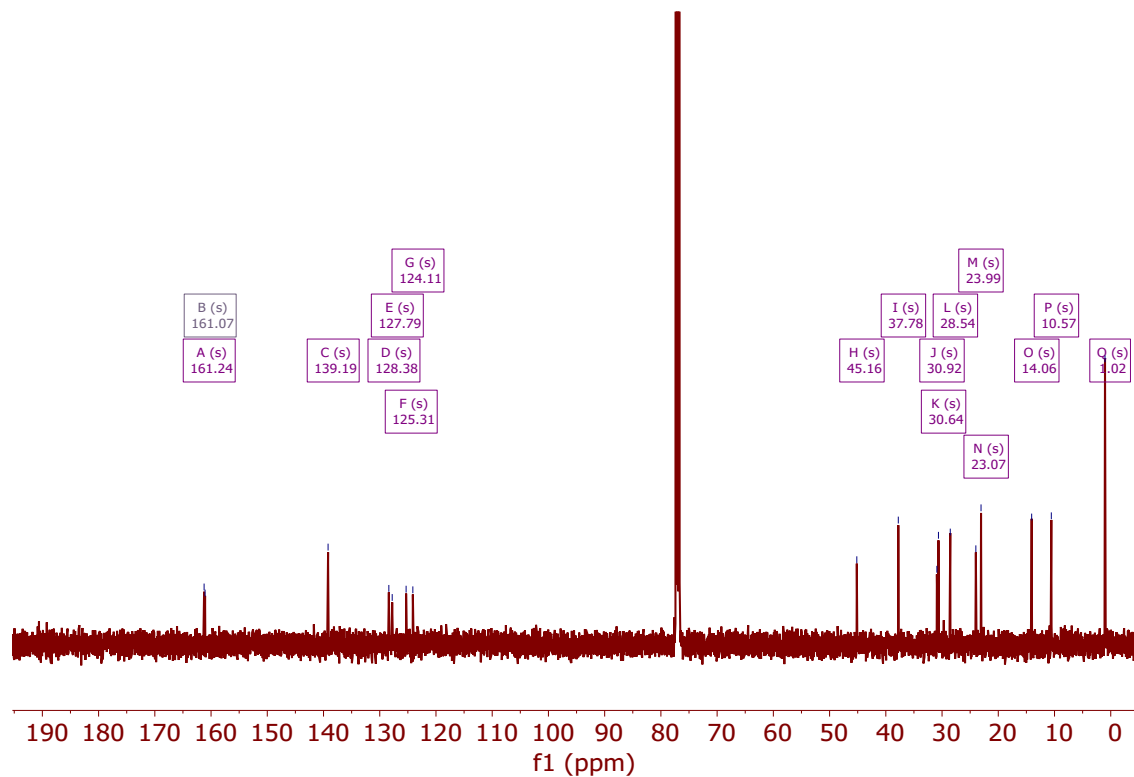
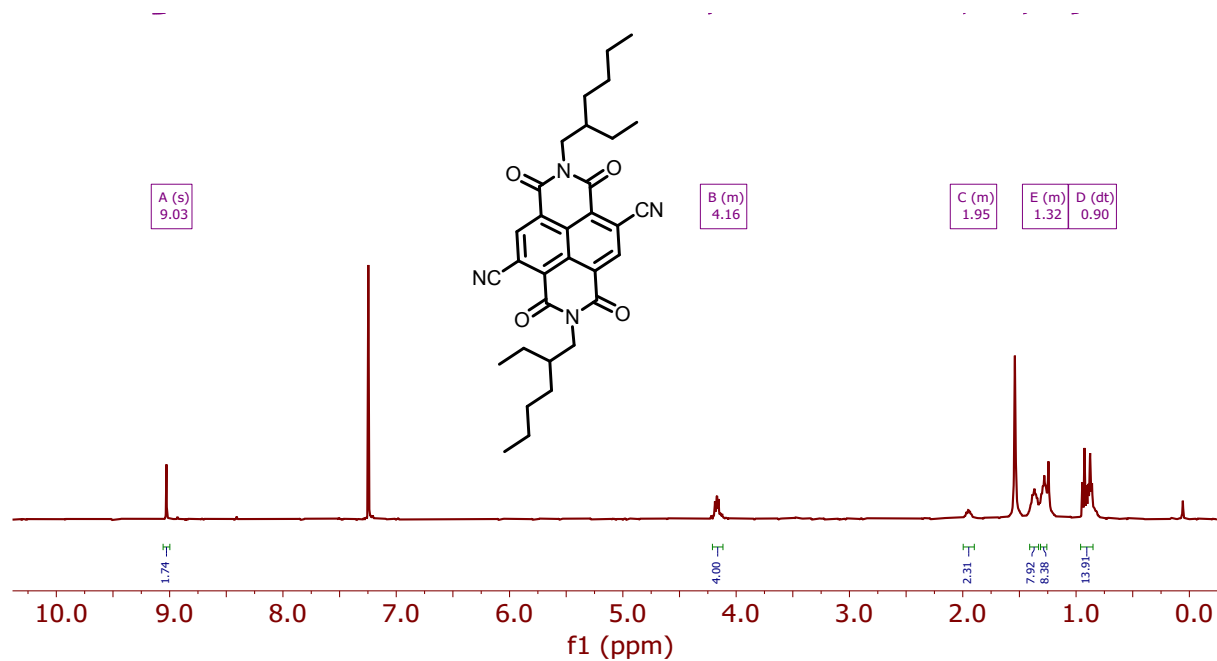
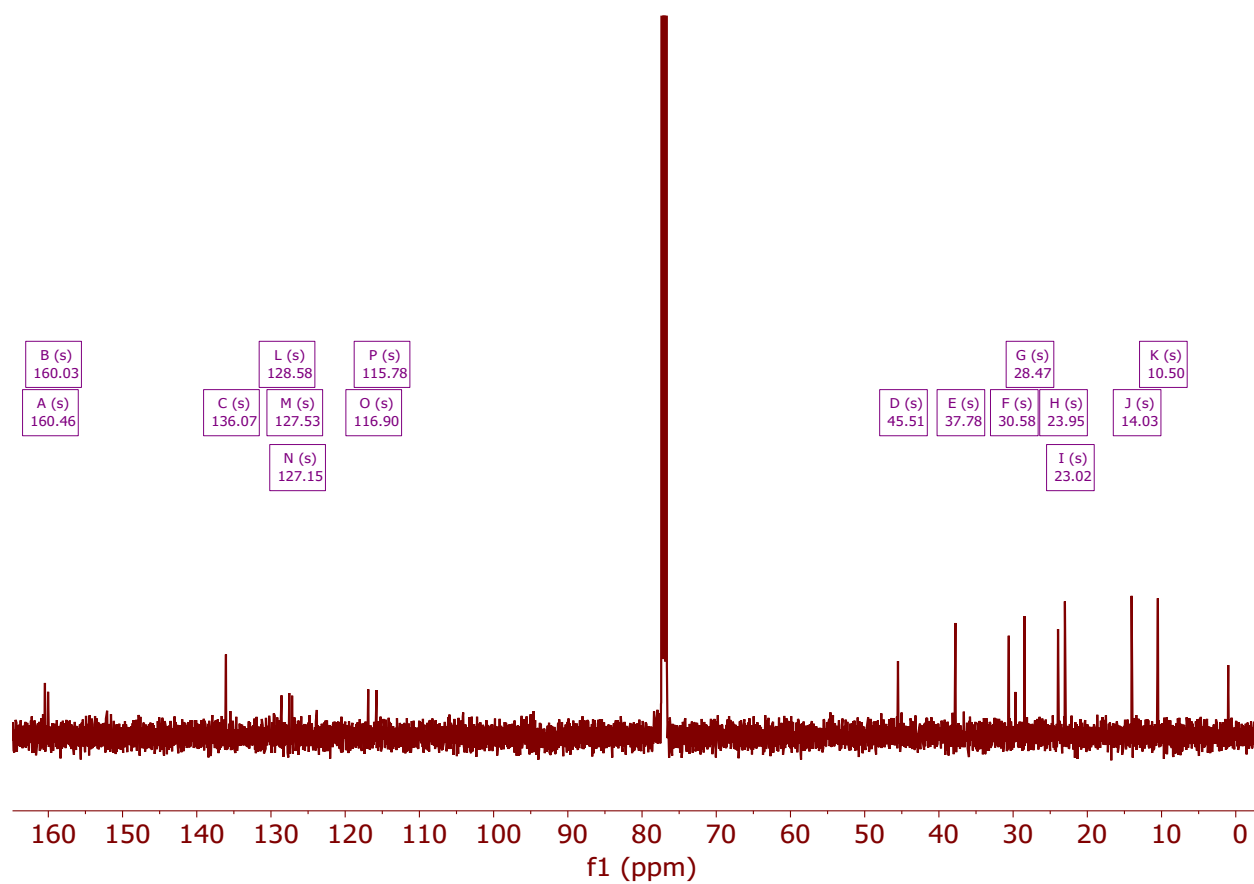


Figure S2. <sup>13</sup>C NMR spectrum of EHNDIBr<sub>2</sub> in CDCl<sub>3</sub>.



**Figure S3.** <sup>1</sup>H NMR spectrum of EHNDICN<sub>2</sub> in CDCl<sub>3</sub>.



**Figure S4.** <sup>13</sup>C NMR spectrum of EHNDICN<sub>2</sub> in CDCl<sub>3</sub>.

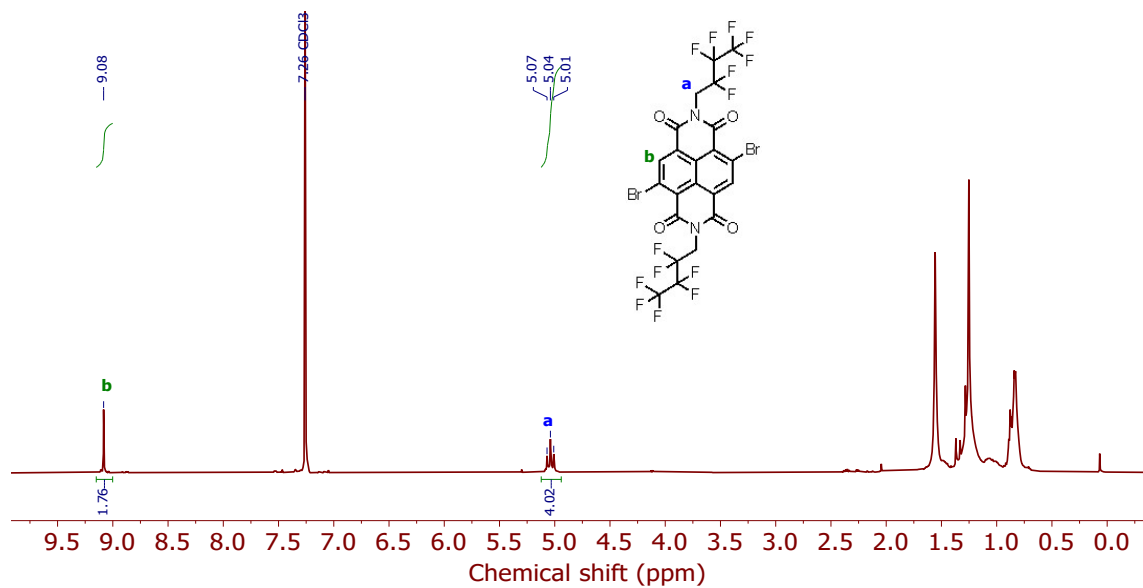


Figure S5.  $^1\text{H}$  NMR spectrum of  $\text{NDIFBr}_2$  in  $\text{CDCl}_3$ .

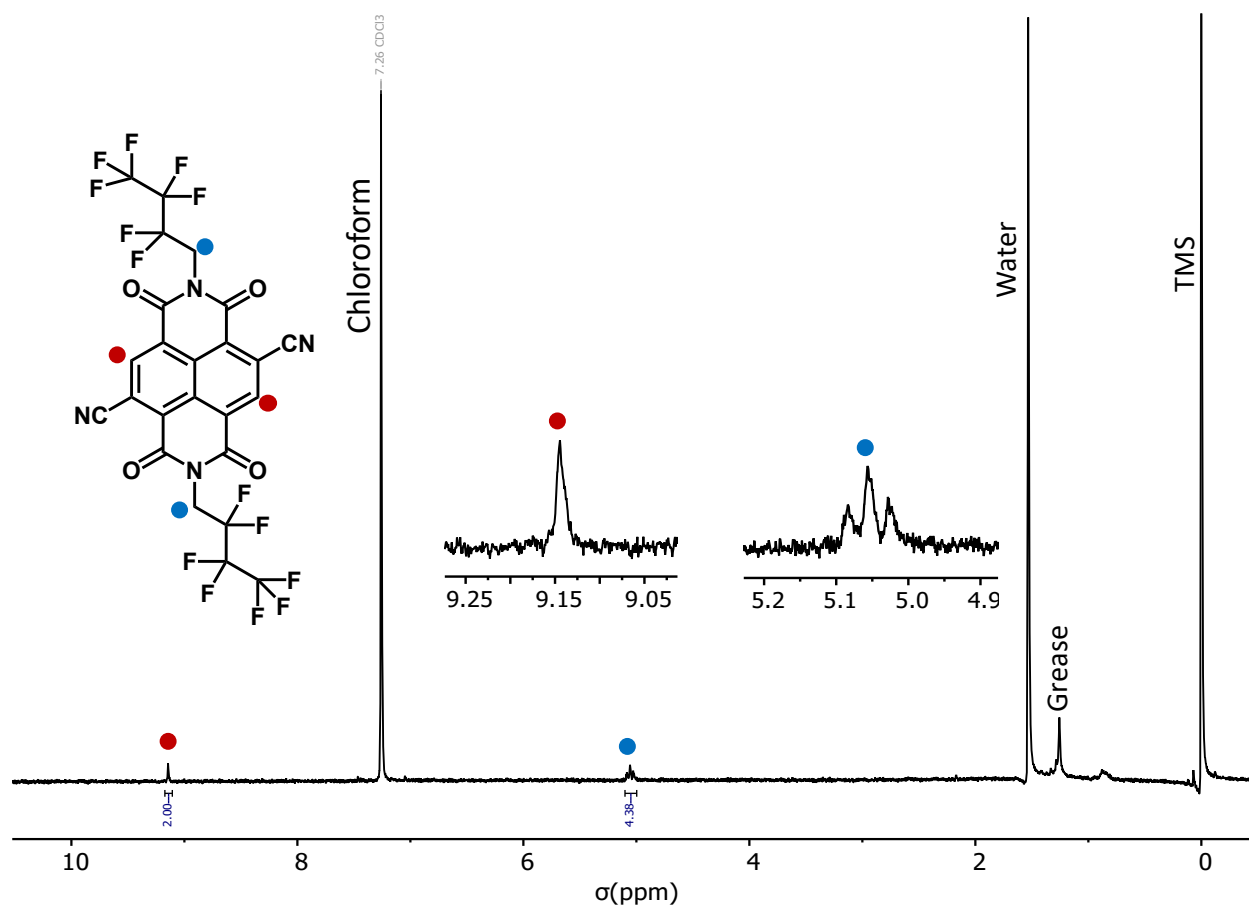
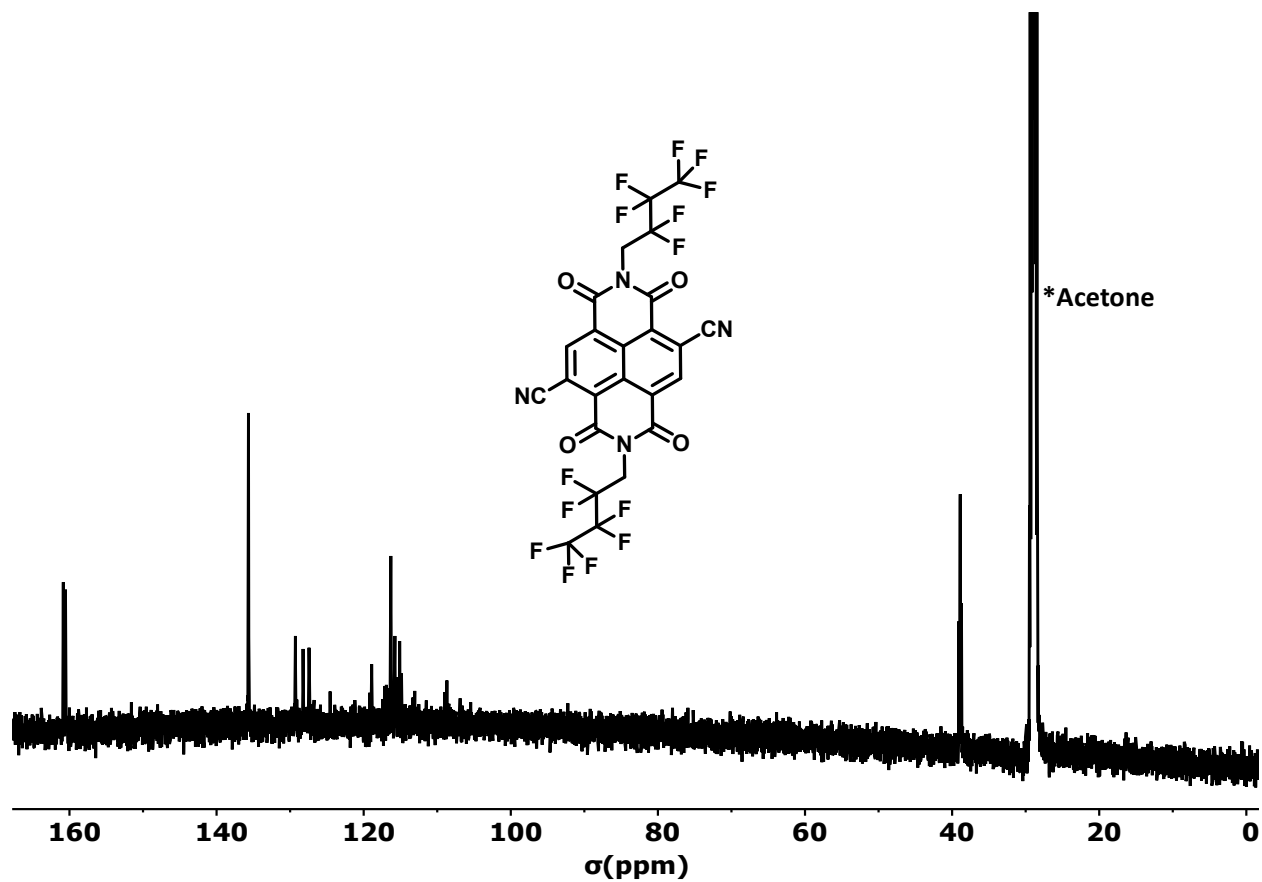
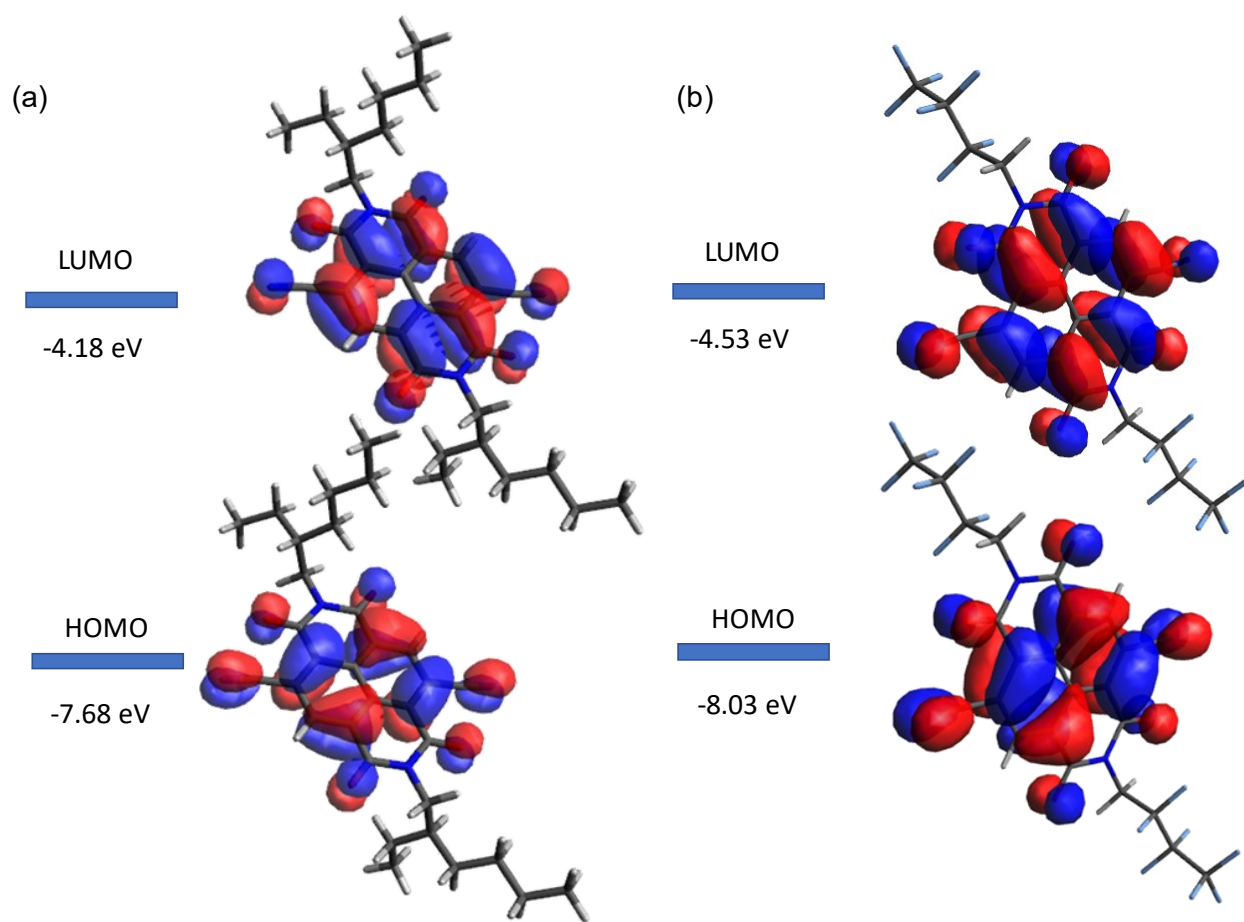


Figure S6.  $^1\text{H}$  NMR spectrum of  $\text{NDIFCN}_2$  in  $\text{CDCl}_3$ .



**Figure S7.**  $^{13}\text{C}$  NMR spectrum of EHNDICN<sub>2</sub> in CDCl<sub>3</sub>.

## 2. Computational calculations:



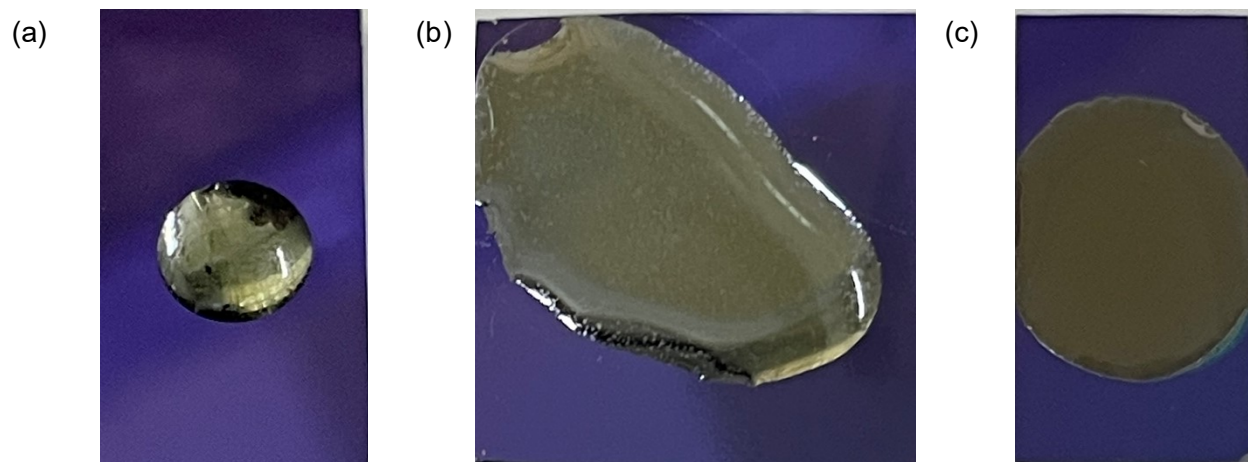
**Figure S8.** HOMO and LUMO levels and the orbital distribution diagram from DFT calculation: (a) EHNDICN<sub>2</sub> and (b) NDICN<sub>2</sub>.

## 3. Cyclic voltammetry (CV):

CV was carried out with the CHI604D instrument. CV for liquid state samples was determined at room temperature using 0.1 M tetrabutylammonium hexafluorophosphate (TBAPF<sub>6</sub>) in dry CH<sub>2</sub>Cl<sub>2</sub> solvent under nitrogen atmosphere with a scan rate of 100 mV/s, where gold wire used as the working electrode; platinum wire as the counter electrode; Ag/AgCl (saturated KCl) as the reference electrode. LUMO energy levels of the compounds were calculated according to the inner reference ferrocene redox couple

versus Ag/Ag<sup>+</sup> in CH<sub>2</sub>Cl<sub>2</sub> by using the formula  $E_{\text{LUMO}} = - [ E_{\text{red}}^{\text{onset}} + 4.8 - E_{\text{Fc}}^{1/2} ]$ .

#### 4. Substrates wettability test:



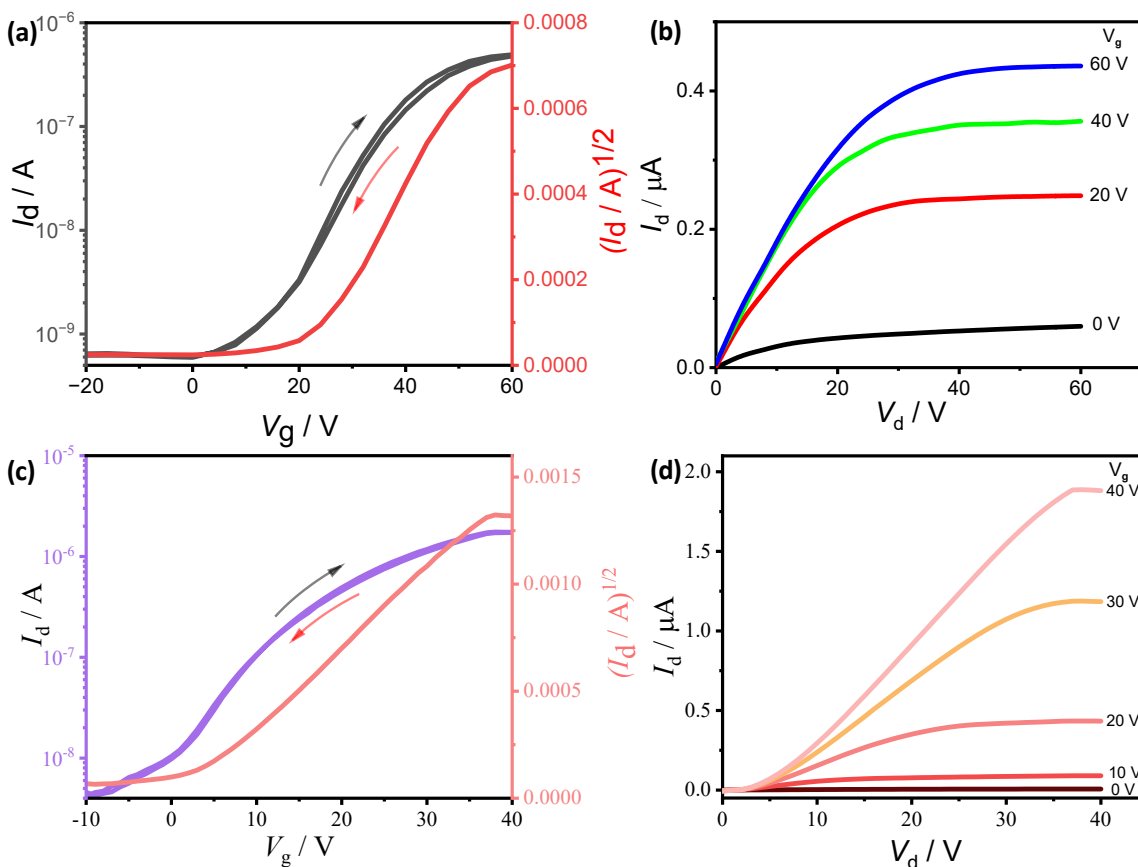
**Figure S9.** Substrate wettability: a drop solution of **NDIFCN<sub>2</sub>** in *o*-DCB on (a) *n*-OTS treated Si/SiO<sub>2</sub>, (b) Bare Si/SiO<sub>2</sub>. (c) **EHNDICN<sub>2</sub>** in CHCl<sub>3</sub> on *n*-OTS treated Si/SiO<sub>2</sub>.

#### 5. Device fabrication procedure (thermal vapor deposited) active layer:

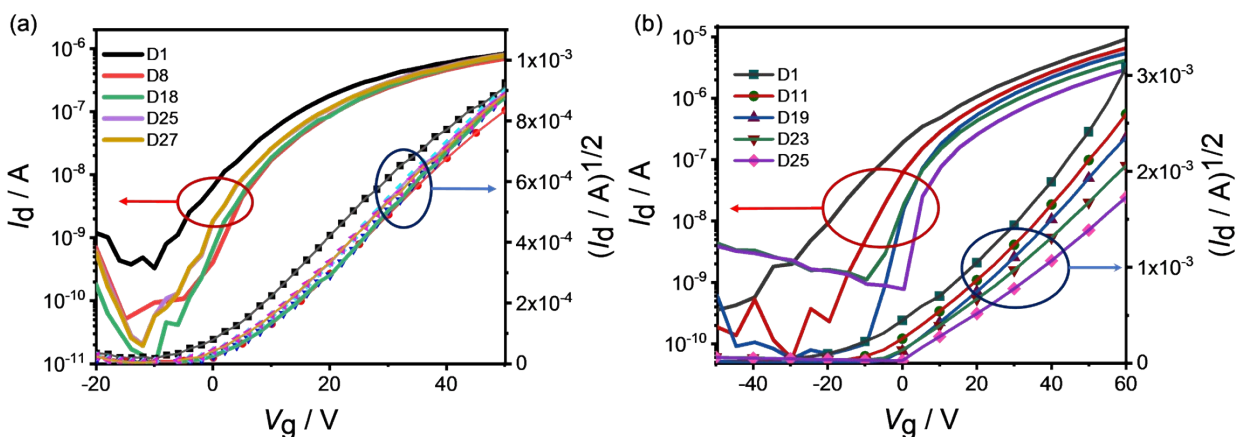
For **EHNDICN<sub>2</sub>**, a bottom gate top contact geometry was used. The glass substrates were cleaned by dipping the substrates in piranha solution for 1 hour followed by rinsing in DI water and drying. 100 nm of aluminum was thermally deposited on the cleaned glass substrates to form the gate electrode of width 1 mm by shadow masking on a glass substrate. A solution of PVA in DI water (100 mg ml<sup>-1</sup>) was prepared and spin-coated with 1000 rpm for 30 s on the gate deposited substrate and dried at 100 °C for 1 hour to form 1 μm thick layer. PVA acts as the first dielectric, over which a 100 nm (3000 rpm 30 s) thick second dielectric layer (PMMA) is coated and dried at 100 °C for 1 hour. After the deposition of gate dielectric layers, a 60 nm (±10 nm) active material **EHNDICN<sub>2</sub>** was deposited by thermal deposition at a temperature of 250 °C under a base pressure of 10<sup>-6</sup> mbar at substrate temperature of 60 °C. Further, Al source–drain electrodes were thermally deposited using shadow masking to form a channel of length (L) 40 μm and width (W) 0.8 mm.



For **NDIFCN<sub>2</sub>**, a bottom contact top gate geometry was used. To extract the optimized charge transport properties, we also fabricated FETs for the same molecules using a vapor deposition technique. The semiconducting films were grown on lithographically patterned 25 nm thick Cr/Au S-D electrode. This was followed by vapor-deposition of the thin films of **NDIFCN<sub>2</sub>** at  $10^{-6}$  Torr, at a rate of 0.2 Å/s to achieve film thickness of up to 40 nm. The temperature of the substrate was set at room temperature during the process of deposition. All the measurements were performed using a semiconductor parameter analyzer B1500.



**Figure S10.** Transfer curves (a) & (c) and output curves (b) & (d) for **NDIFCN<sub>2</sub>** & **EHNDICN<sub>2</sub>** respectively for the devices made of Physical Vapor Deposition (PVD) method.



**Figure S11.** Transfer curves of the air-exposed devices at various intervals of time: a) **NDIFCN<sub>2</sub>** and b) **EHNDICN<sub>2</sub>**. (D = Day).

## 6. Single crystal structure:

Single crystals of **EHNDICN<sub>2</sub>** were obtained from chloroform and *o*-dichlorobenzene solvent mixture by slow solvent evaporation and for **NDIFCN<sub>2</sub>**, the solvent mixture was chloroform and ethyl acetate. **NDIFCN<sub>2</sub>** recrystallizes in the monoclinic space group of  $P2_1/c$  and **EHNDICN<sub>2</sub>** as in the triclinic space group of  $P\bar{1}$ . A non-classical hydrogen bonding ( $d_{C-H\cdots O} = 2.36$  Å) and C-H interaction ( $d_{C-H\cdots C} = 2.86$  Å) are the major interactions that control the overall crystal packing of **EHNDICN<sub>2</sub>**. There is slipped packing of the  $\pi$ -conjugated core with an inter-planar 3.34 Å  $\pi$ -stacking distance between two **EHNDICN<sub>2</sub>** molecules. The low crystal packing density ( $1.3$  g cm<sup>-3</sup>) and the slipping angle along the long molecular axis is 67.09° and the short is 40.30° which indicates the low  $\pi$ - $\pi$  overlapping between the molecules (figure S10c) and it reflects on the charge carrier mobility as low. In the case of **NDIFCN<sub>2</sub>**, along with non-classical hydrogen bonding ( $d_{C-H\cdots O} = 2.62$  Å), H-F ( $d_{C-H\cdots F} = 2.57, 2.61$  Å) and F-F interactions ( $d_{C-F\cdots F} = 2.85$  Å) are the major interactions in the crystal packing (figure S11b). Including these interactions, strong C-F interactions ( $d_{C-F\cdots C} = 2.90, 3.13$  and  $3.14$  Å) help to pack with a high packing density ( $1.95$  g cm<sup>-3</sup>) in its crystal packing. Although having a high packing density, there is almost no direct  $\pi$ - $\pi$  overlap between the two **NDIFCN<sub>2</sub>** molecules. In figure S10b, it is visible that there is the incorporation of a fluoro-alkyl chain through the  $\pi$ - $\pi$  stacking direction. It prevents the  $\pi$  core-overlapping and



## X-Ray Crystallographic Analysis:

	<b>EHNDICN<sub>2</sub></b>	<b>NDIFCN<sub>2</sub></b>
Chemical formula	C32 H34 N4 O4	C24 H6 F14 N4 O4
Crystal System	triclinic	monoclinic
Space Group	$P\bar{1}$	P 1 21/c 1
a (Å)	5.3597	9.6378
b (Å)	8.2900	13.1727
c (Å)	15.7629	10.2479
$\alpha$ (°)	99.995	90
$\beta$ (°)	93.825	117.064
$\gamma$ (°)	95.201	90
V (Å <sup>3</sup> )	684.48	1158.57
Z	1	4
D (g cm <sup>-3</sup> )	1.307	1.950
R <sub>1</sub> (%)	9.67	3.39

**Table S1.** Crystallographic data obtained from single crystal XRD experiment.

## X-Ray Crystallographic interactions.

<b>NDIFCN<sub>2</sub></b>	<b>distance (Å)</b>	<b>EHNDICN<sub>2</sub></b>	<b>distance (Å)</b>
H9B-F13	2.569	O001-C00K	3.12
F17-F14	2.85	C00C-C006	3.38
F17-C22	3.14	N004-H4B	2.58
H3-O21	2.623	N004-H00C	2.74
H3-F16	2.615	H00B-O002	2.36
C3-F16	2.896	O001-H00Q	2.35
F18-H9A	2.618		
C22-F17	3.14		
C5-F15	3.13		

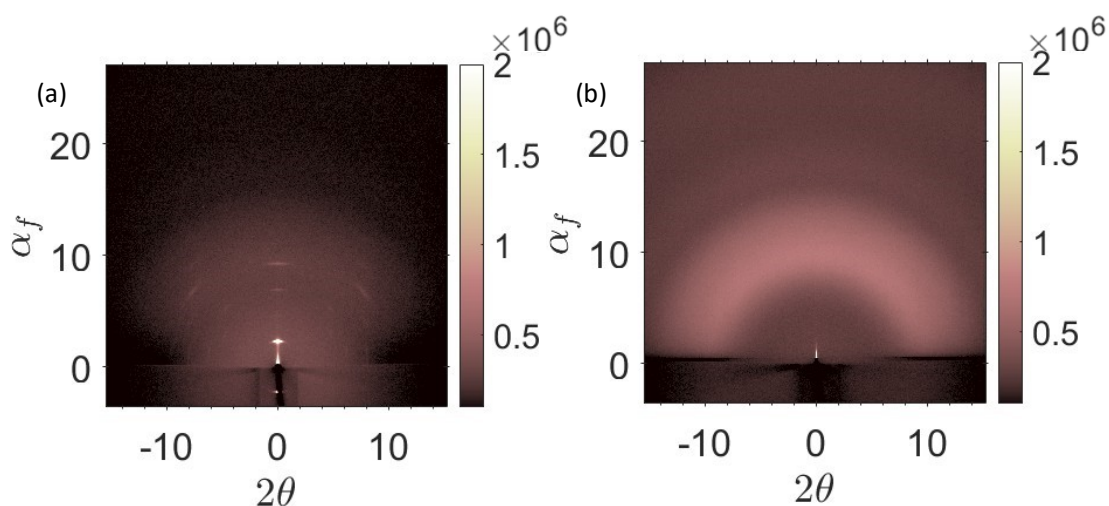
**Table S2.** Different types of non-classical interactions and their distances in their crystal state packing.

## 7. Film morphology analysis:

An atomic force microscopy experiment was carried out on NT-MDT (model no. AP-0100) in semi-contact mode. The morphology of the surfaces was investigated using field emission scanning electron microscopy (FE-SEM). The images were taken using an FE-SEM apparatus (ZEISS scanning microscope-ZSM-S 55 VP). The samples were prepared by keeping the conditions the same as device fabrication. For the spin-coated film, the roughness measured from AFM measurement is 2.4 and 2.8 nm, for **NDIFCN<sub>2</sub>** and **EHNDICN<sub>2</sub>** respectively. Low roughness indicates the smoothness of the films.

## 8. Film state-wide angle X-ray diffraction (WAXRD) and 2D grazing incident XRD (2D GIXRD):

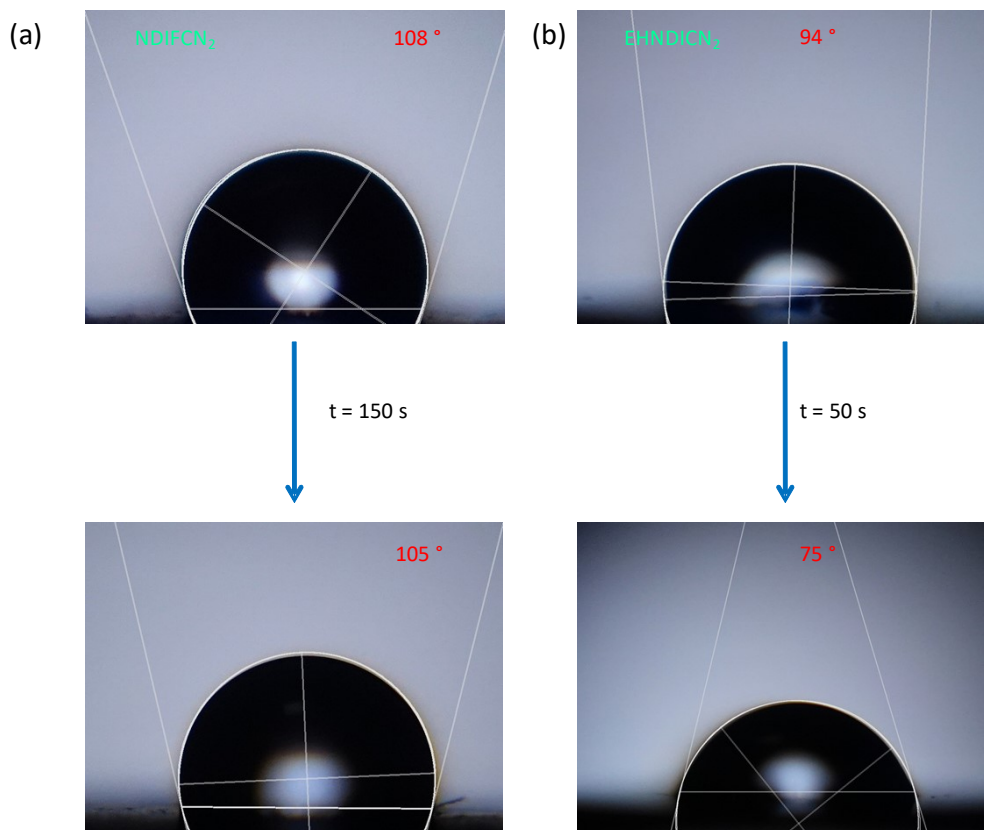
Film state-wide angle X-ray diffraction (WAXRD) measurements were conducted for **EHNDICN<sub>2</sub>** on OTS-modified SiO<sub>2</sub> and **NDIFCN<sub>2</sub>** on bare SiO<sub>2</sub> substrates. A solution of **EHNDICN<sub>2</sub>** was prepared in Chloroform (5 g L<sup>-1</sup>) at 45 °C and **NDIFCN<sub>2</sub>**, a solution of 4-5 g L<sup>-1</sup> in *o*-dichlorobenzene (*o*-DCB) was prepared at 120 °C and stirring condition. For **NDIFCN<sub>2</sub>**, the film was made by drop casting and for **EHNDICN<sub>2</sub>**, the film was made by spin coating with 1500 rpm spin speed for 40 s. The substrates were further subjected to thermal annealing at 120 °C for 10 minutes and then transferred to a vacuum desiccator. For 2D XRD measurements, samples were prepared on top of glass substrate keeping the device fabrication conditions same.



**Figure S14.** 2D GIXRD pattern (a) **EHNDICN<sub>2</sub>**, (b) **NDIFCN<sub>2</sub>**.

## 9. Contact angle measurement:

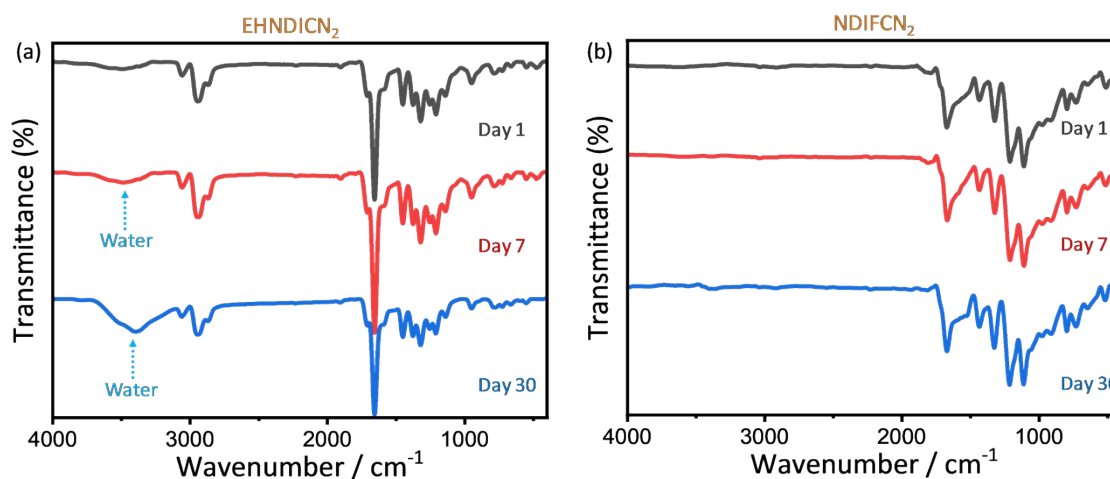
For water contact angle measurement, we made the film on top of Si/SiO<sub>2</sub> substrates keeping all the conditions the same as device fabrications. The greater contact angle of **NDIFCN<sub>2</sub>** (108 °) than **EHNDICN<sub>2</sub>** (94 °) indicates the higher hydrophobicity in the case of the fluorinated alkyl chain containing **NDI**. As a result, we observed the higher ambient stable device in the case of **NDIFCN<sub>2</sub>**. Contact angle measurements were repeated, with the same drops left on the substrates for a duration. Results showed that for **NDIFCN<sub>2</sub>**, there was scarcely any change in the contact angle even after 150 seconds, with a marginal decrease from 108 ° to 105 °. Conversely, **EHNDICN<sub>2</sub>** exhibited a significant alteration in contact angle after just 50 seconds, decreasing from 94 ° to 75 °. These findings indicate the superior hydrophobicity of **NDIFCN<sub>2</sub>** compared to **EHNDICN<sub>2</sub>**. Live video was also added.



**Figure S15.** The contact angle of a water droplet on the thin films of a) **NDIFCN<sub>2</sub>** and b) **EHNDICN<sub>2</sub>**, over a period of seconds.

## 10. FTIR Spectroscopy Measurements:

For FTIR spectroscopy, the compound was drop-casted from a chloroform solution onto an IR fused quartz substrate. Subsequently, it was annealed at 120 °C for 10 minutes and then placed in a vacuum desiccator overnight. Measurements were conducted on day 1, day 7, and day 30.



**Figure S16.** FTIR spectroscopy of (a) EHNDICN<sub>2</sub> and (b) NDIFCN<sub>2</sub> films exposed to ambient atmosphere for 30 days.

## 11. References:

- 1 B. A. Jones, A. Facchetti, T. J. Marks and M. R. Wasielewski, *Chem. Mater.*, 2007, **19**, 2703–2705.